# Polarized source and beam injection system for MESA

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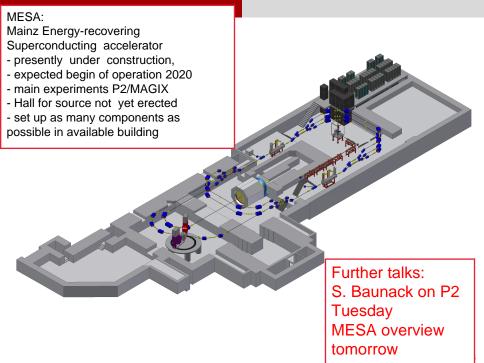
Johannes Gutenberg. Universität Mainz

presenting work of the MESA injector group (I. Alexander, A. Bünning, S. Friedrich, L. Hein, B. Le Droit, P. Heil, Chr. Matejeck, C. Stoll)

> SPIN 2016 Urbana Champaign September 28, 2016







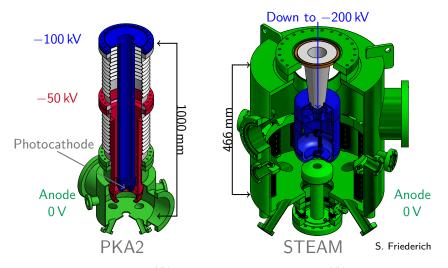
## **STEAM**

#### Small Thermalized Electron Source at MESA

## New (wrt MAMI):

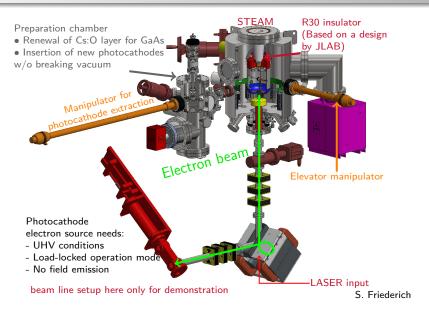
- -higher current (MAGIX polarized \*10) =1mA
- more sophisticated spin control (P2)
- 1300 MHz operation (instead of 2499)
- scientific project: explore high brightness near bandgap emission at "relevant" bunch charges for radiation sources

### Comparison between STEAM ↔ PKA2 (existing source)

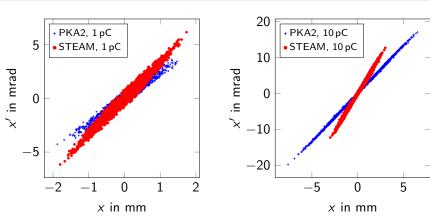


Difference: PKA2:  $E_{acc} \approx 1 \, \frac{MV}{m} @ 100 \, kV$ , STEAM:  $E_{acc} \approx 2.5 \, \frac{MV}{m} @ 100 \, kV$ 

### Finished design concept of electron source



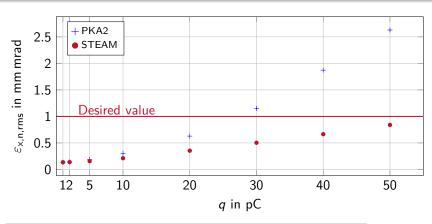
### Comparison between STEAM ↔ PKA2 @ 100 kV



### Further simulation parameters

U=100 kV,  $k_{\rm B}T=200$  meV,  $\sigma_0=0.5$  mm,  $t_{\rm bunch}=2\cdot t_{\rm cutoff}=200$  ps Drift length =200 mm +  $d_{\rm cathode,anode}$ 

## Comparison between STEAM ↔ PKA2 @ 100 kV

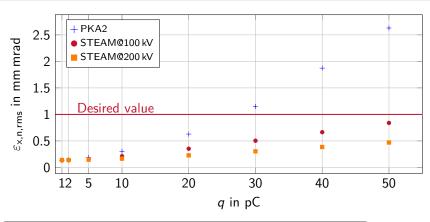


#### Further simulation and calculation parameters

U=100 kV,  $k_{
m B}T=200$  meV,  $\sigma_0=0.5$  mm,  $t_{
m bunch}=2\cdot t_{
m cutoff}=200$  ps Drift length =200 mm +  $d_{
m cathode,anode}$ 

$$\varepsilon_{\mathsf{n,rms}} = \beta \gamma \sqrt{\langle x^2 \rangle \cdot \langle x'^2 \rangle - \langle x \cdot x' \rangle^2}$$

### Comparison between STEAM ↔ PKA2 @ 100 kV | 200 kV

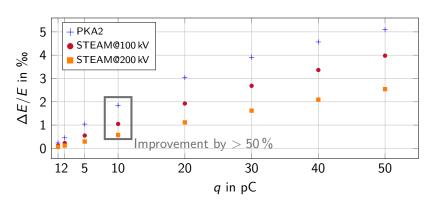


#### Further simulation and calculation parameters

U=100 kV|200 kV,  $k_{\rm B}T=200$  meV,  $\sigma_0=0.5$  mm,  $t_{\rm bunch}=2\cdot t_{\rm cutoff}=200$  ps Drift length =200 mm +  $d_{\rm cathode,anode}$ 

$$\varepsilon_{\text{n,rms}} = \beta \gamma \sqrt{\langle x^2 \rangle \cdot \langle x'^2 \rangle - \langle x \cdot x' \rangle^2}$$

### Comparison between STEAM ↔ PKA2 @ 100 kV | 200 kV



#### Further simulation and calculation parameters

U=100 kV/ 200 kV/,  $k_{\rm B}T=200$  meV/,  $\sigma_0=0.5$  mm,  $t_{\rm bunch}=2\cdot t_{\rm cutoff}=200$  ps Drift length =200 mm +  $d_{\rm cathode,anode}$ 

$$\frac{\Delta E}{E} = \frac{E_{\text{max}} - E_{\text{min}}}{e \cdot U + m_e c^2}$$

### Source assembling finished and ready for baking out and HV-processing

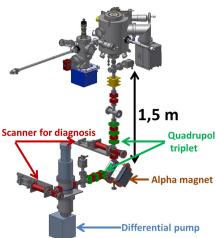


Preparation chamber

lon getter pump

## Working platform and beamline framework was finished recently and source was mounted



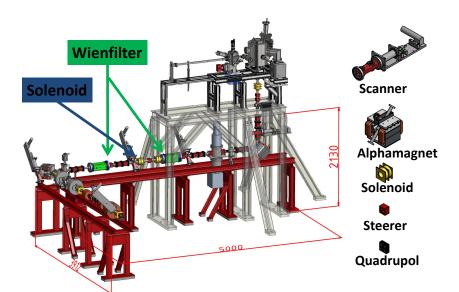


Actual setup

Planned setup in autumn

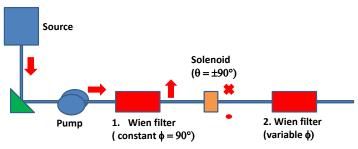
## Spinrotation System

## Spinrotating system at MELBA (MESA low energy beam apparatus)

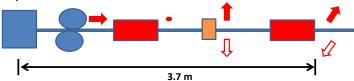


## Working principle

#### Side view:

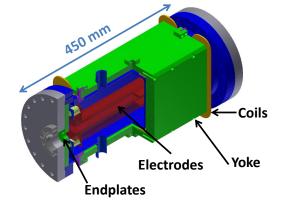






#### Wienfilter

- 100 keV version exists and works
- Two in stock



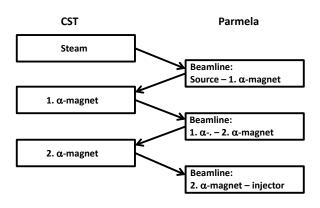
#### Solenoid

- $\blacksquare \int B_{\parallel} ds = 0.10 \, \text{T m for } 100 \, \text{keV}, \, 90^{\circ}$
- Under design

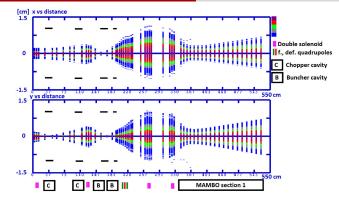
## Laser System

- Current Laser system at MAMI is a MOPA (Master Oszillator Power Amplifier)
- It is temperature stabilized and an external feedback loop is responsible for beam current stabilization
- 250 mW are available at the photocathode
- Quantum efficiency of GaAs/GaAsP superlattice at 780 nm is 2 mA/W
- With 150  $\mu$ A we get 14  $\frac{C}{d}$  or 4  $\frac{mAh}{d}$
- We assume to get 200 C per lifetime of one cathode
- ⇒ Able to provide 14 days of continous beam
- ⇒ Able to supply the P2 experiment with beam

## **Beamline Simulation**



Use result particle distribution of one program as start distribution for the other.



Parmela simulation from second alpha magnet to the end of the first MAMBO section for a beam current of 1.3 mA.

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## Summary & Outlook

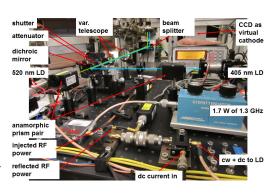
### Summary & Outlook

- STEAM can provide P2 experiment
- Backup source PKA2
- Spinrotating system soon available
- With current Laser system, source, cathodes we can provide sufficent beam current and beam availability for P2 experiment
- Beamline can handle beamcurrent
- Infrastructure (e. g. cooling water) is ready to use
- Build up first part of beamline till autumn
- Finish whole low beam energy transport within the next year

## Thank you for your attention!

## **Backup Slides**

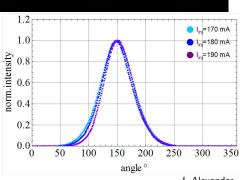
- LASER diodes  $\rightarrow$  cheap
- three available wavelengths (405 nm, 520 nm, 780 nm)
- $@780 \text{ nm} \rightarrow QE = 0.5 \%$ ; pol.  $\approx 80 \%$
- @405 nm  $\rightarrow$  QE = 15%; pol.  $\approx 0\%$
- lue DC- or pulsed mode ightarrow longer lifetime
- RF synchronized



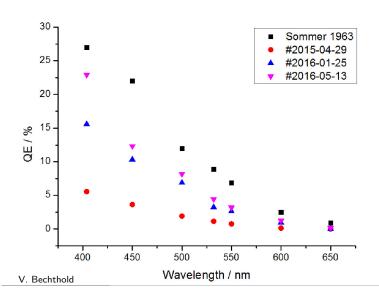
I. Alexander

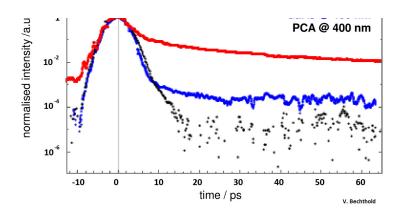


- green laser diode
- $\lambda = 520 \, \text{nm}$
- $P = 120 \, \text{mW}$
- $I_{th} = 120 \, \text{mA}$
- transmission  $@120^{\circ} > 95\%$
- low beam  $current < 1\,\mu A$



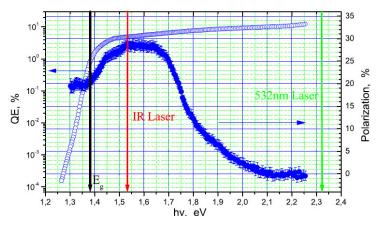
I. Alexander





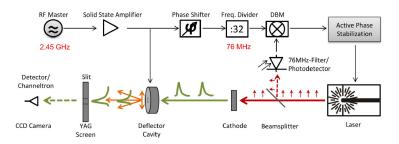
### Potassium Cesium Antimonid (PCA) versus GaAs photocathodes

PCA photocathodes promise high quantum efficiency, fast response time and low thermal emittance while being 100 fold more robust.

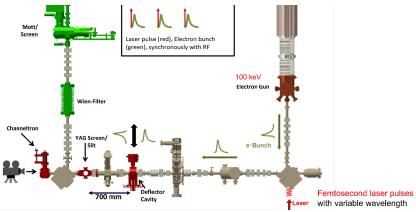


Quantum efficiency and polarisation as function of the photon energy for p-doped bulk GaAs crystal. By Y. Yashin, 2006

#### i inicipie, radionequency streak method



- Conversion of the longitudinal profile into transversal profile by TM-110 RF Deflector Cavity
- Electron bunches must be emitted synchronously to RF Master→ stable spatial image of the bunch is generated
- Pulse image shifted over slit by varying the phase of the laser pulse relative to RF
- Bunch profile sampled by measuring the dependence of the current or picture on YAG-screen



- TM110 cavity transforms longitudinal beam profile into a transversal one
   synchronization of electron bunches and RF cavity needed for observation
- resulting intensity distribution represents the time dependency of electrons in one bunch
- · measured by YAG-screen and channeltron

Victor Bechthold, EWPPAA 2016

Status K:CsSb cathodes and time response measurements

. . .





 $\lambda = 405 \text{ nm}$ 

P = 200 mW

 $I_{th}$  = 25 mA transmission @ 120°

> 99%

